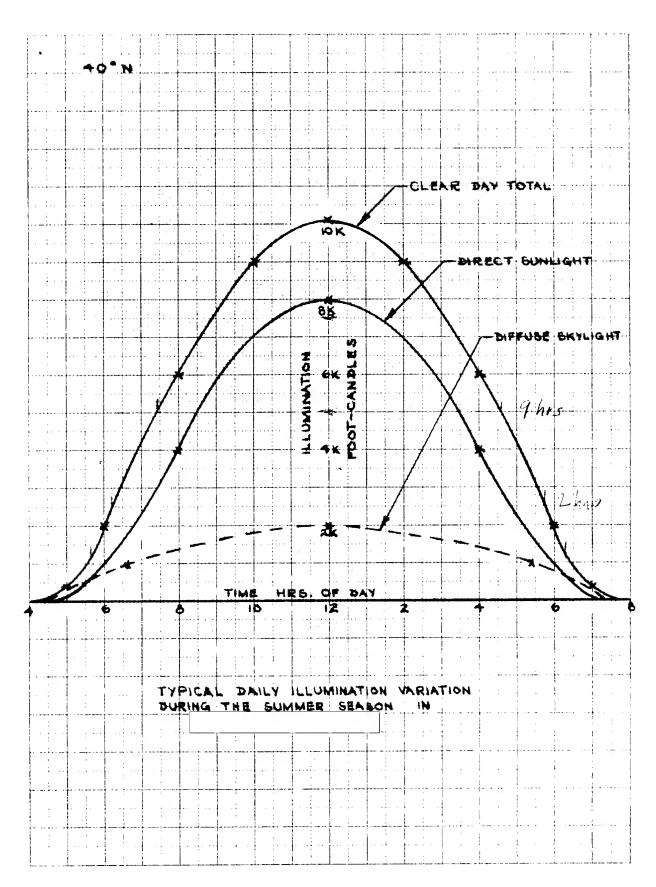
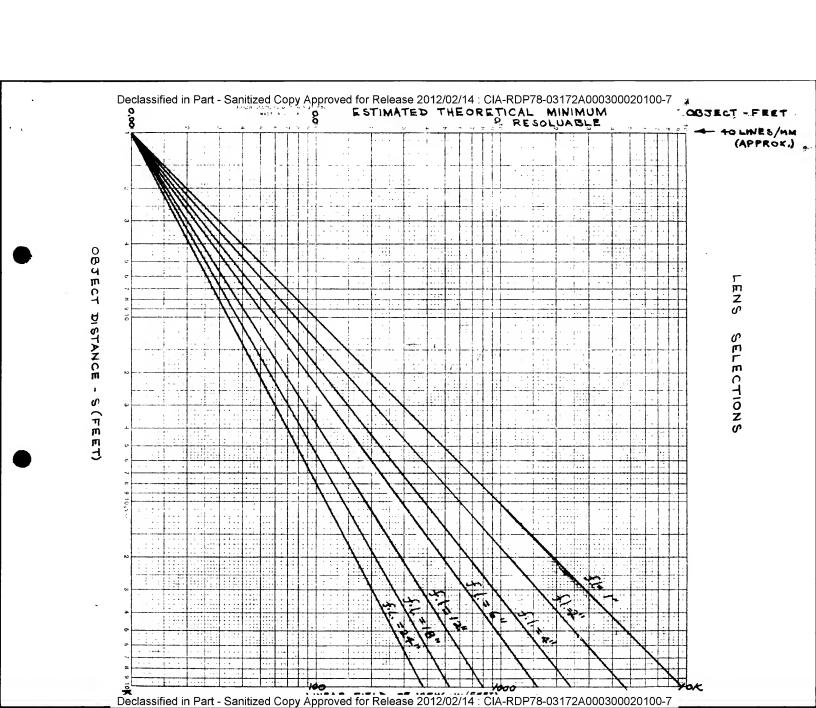
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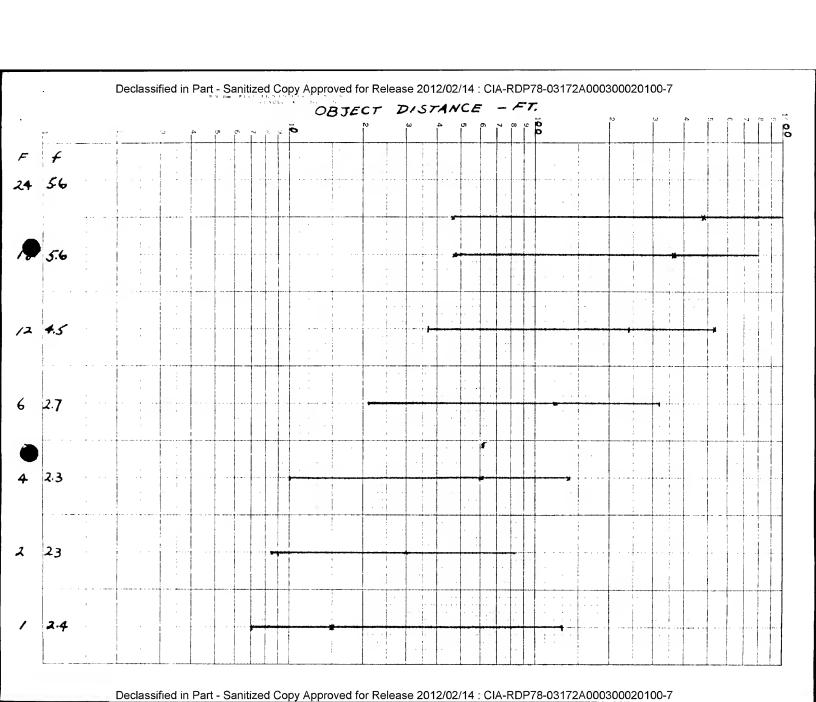
## GENERAL EVALUATION OF EXPOSURE CONTROL SYSTEMS

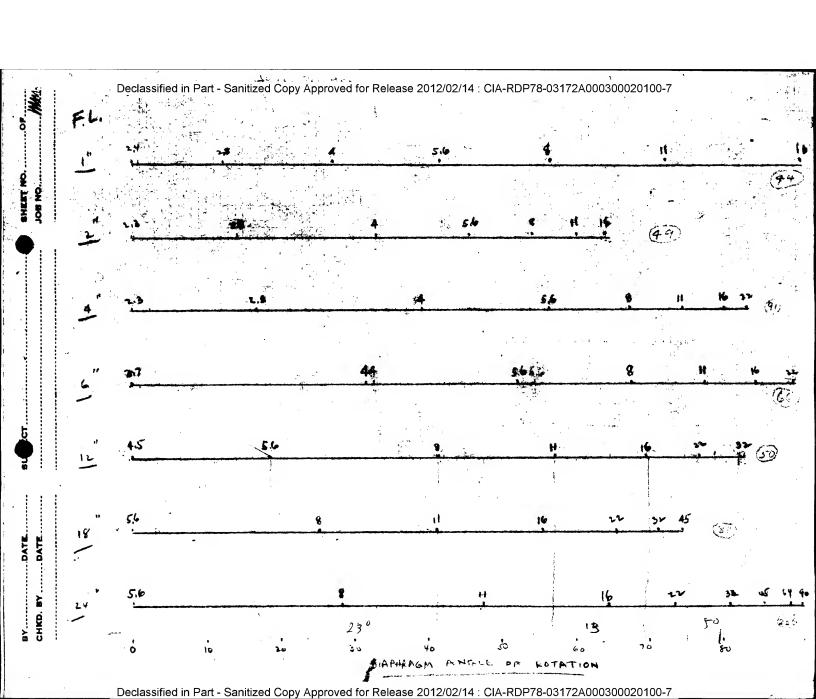
· · · · · · · · · · · · · · · · · · ·	IRIS CONT PRO HIGH STATIC RESOLUTION GREATER DEPTH OF FIELD	CON  GREATER POWER  CONSUMPTION  LOW SYSTEM  RELIAGILITY  HIGH MECHANICAL  COMPLEXITY  LESS DYNAMIC  RANGE  LOW DYNAMIC  RESOLUTION	TIME CONTROL  PRO HIGH SYSTEM LESS DEPTH RESOLUTION RESOLUTION HIGH DYNAMIC RANGE QUICK DELIVERY	COMBINED CONTROL  PRO  MAX. DYNAMIC RANGE CAPAGILITY  MAX. OPERATING TIME  MAX. CONTRAST MAX. RESOLUTION  PRODUCTION TIME  CONTROL  PRODUCTION TIME		
CONTINUOUS	MAX. CONTRAST  MAX.  RESOLUTION  SIMPLICITY	MORE POWER REQUIREMENT MORE COMPLEXITY  LESS INFORMATION	SAME AS IRIS CONTROL	SAME AS IBIS CONTROL		
STEP	RELIABILITY	CONTEND				
OPEN LOOP	SIMPLICITY	INACURACY				
CLOSE Loop	MORE RELIABILITY	MORE COMPLEXITY	SAME AS IRIS CONTROL	SAME AS IRIS CONTROL		
SINGLE LENS	SIMPLICITY  RELIABILITY  LOW COST  MORE COMPACT	WORK WITH	'/ SAME AS IRIS CONTROL	SAME AS IRIS CONTROL		
DUAL LENS	MORE WORKING SPACE GETTER APPROXIMATION	MORE MECHANICAL COMPLEXITY				



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Depth of Field Calculation for CD-182 Lens

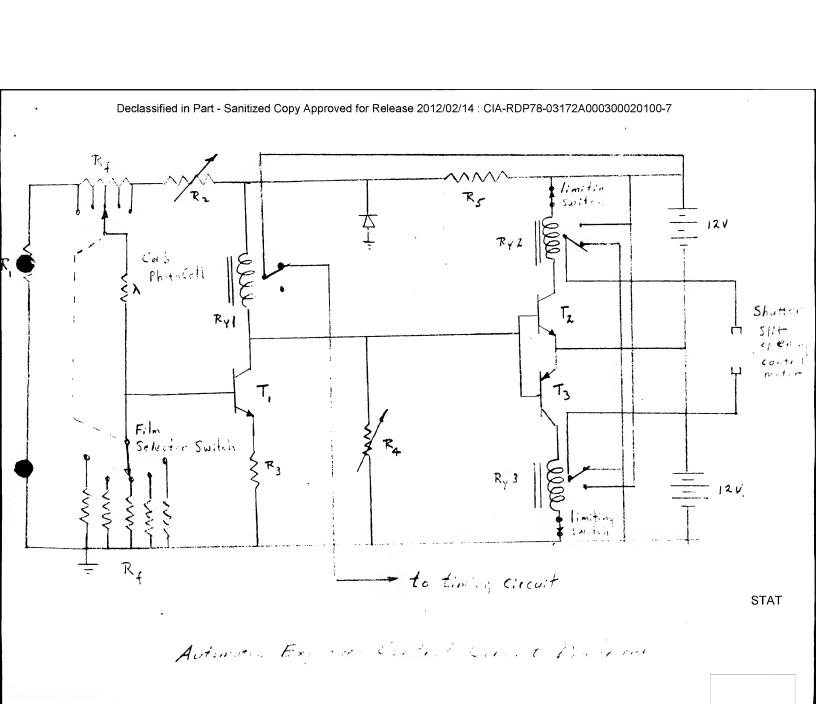
$$D = D_{epin of field} = D_N + D_F$$

$$D_N = \frac{HS}{H+S} \qquad D_F = \frac{HS}{H-S}$$

$$H = hyperfocal distance = \frac{F^2}{fC} \times .083$$

$$for C_C = 0.002 \qquad = 41.5 F/f$$

F	f	5	H	HS	H-S	S +H	$\mathcal{D}_{\mathcal{F}}$	$\mathcal{D}_{\mathcal{N}}$	D
1"	2.4	15	17.3	<b>2</b> 60	2.3	32.3	//3	8	12/
2"	2.3	30	72	2#60	42	102	57.5	21.6	73
411	2,3	60	239	17,400	229	349	>6	5	/ 2 %
6"	2.7	120	554	6.65×18	<b>4</b> 34	674	199	99	298
12"	4.5	2 <b>4</b> o	/530	3.19×105	1190	1570	293	203	40%
13"	sib	360	24 00	8.65x13	2040	2760	4=+	3/3	737
24"	5,6	480	4270	2.06 x 10	3790	4750	547	43-	977



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